



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Cheung, et al.

Serial No.: 10/647,959

Confirmation No.: Unknown

Filed: August 26, 2003

For: Plasma Processes for  
Depositing Low Dielectric  
Constant Films

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Group Art Unit: 2812

Examiner: Unknown

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>12/3</u> , 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.	
<u>12/3/03</u> Date	 Signature

INFORMATION DISCLOSURE STATEMENT

The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.


While the information submitted in this Information Disclosure Statement may be material pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication, or other information referred to therein is prior art for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97, this Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possibly material information as defined under 37 CFR § 1.56(a) exists.

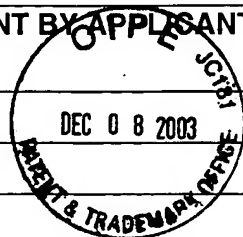
The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/3032.C7/KMT.

Respectfully submitted,

  
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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. AMAT/3032.C7/DSM /LOW K/JW	Serial No. 10/647,959
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>		Applicant Cheung, et al.	Confirmation No. Unknown
(Use several sheets if necessary)		Filing Date August 26, 2003	Group 2812
Examiner	Unknown		

**U.S. Patent Documents**

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A1	6,642,157	11/04/2003	Shioya, et al.	438	789	12/22/2000
	A2	6,596,655	07/22/2003	Cheung, et al.	438	789	09/19/2001
	A3	6,583,071	06/24/2003	Weidman, et al.	438	787	10/18/2000
	A4	6,583,048	06/24/2003	Vincent, et al.	438	623	08/31/2001
	A5	6,582,777	06/24/2003	Ross, et al.	427	551	02/17/2000
	A6	6,562,690	05/13/2003	Cheung, et al.	438	400	06/13/2000
	A7	6,559,520	05/06/2003	Matsuki, et al.	257	642	04/25/2002
	A8	6,548,899	04/15/2003	Ross	257	750	12/04/2000
	A9	6,541,398	04/01/2003	Grill, et al.	438	780	06/19/2002
	A10	6,537,929	03/25/2003	Cheung, et al.	438	790	05/25/2000
	A11	6,531,714	03/11/2003	Bacchetta, et al.	257	77	12/14/1998
	A12	6,486,082	11/26/2002	Cho, et al.	438	789	06/18/2001
	A13	6,479,409	11/12/2002	Shioya, et al.	438	790	02/23/2001
	A14	6,479,110	11/12/2002	Grill, et al.	427	577	09/27/2001
	A15	6,455,445	09/24/2002	Matsuki	438	789	03/28/2001
	A16	6,441,491	08/27/2002	Grill, et al.	257	759	01/25/2001
	A17	6,437,443	08/20/2002	Grill, et al.	257	758	09/27/2001
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	A19	6,340,628	01/22/2002	Van Cleemput, et al.	438	586	12/12/2000

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B1	99/21706	05/06/1999	WO	B22B	09/04	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B2	00/19498	04/06/2000	WO	H01L	21/027	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B3	99/41423	08/19/1999	WO	C23C	----	<input type="checkbox"/>	<input checked="" type="checkbox"/>
	B4	1 176 226 A1	01/30/2002	EP	C23C	16/32	<input type="checkbox"/>	<input checked="" type="checkbox"/>

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Examiner Unknown		Filing Date August 26, 2003	Group 2812

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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A20	6,331,494	12/18/2001	Olson, et al.	438	770	12/30/1999
	A21	6,312,793	11/06/2001	Grill, et al.	428	312.6	05/26/1999
	A22	6,153,537	11/28/2000	Bacchetta, et al.	438	763	12/22/1995
	A23	6,147,009	11/14/2000	Grill, et al.	438	780	06/29/1998
	A24	6,140,226	10/31/2000	Grill, et al.	438	637	07/30/1998
	A25	6,124,641	09/26/2000	Matsuura	257	759	12/08/1997
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	A30	5,989,998	11/23/1999	Sugahara, et al.	438	623	08/28/1997
	A31	5,554,570	09/10/1996	Maeda, et al.	437	235	01/09/1995
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*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B5	1 354 980 A1	10/22/2003	EP	C23C	16/40	<input type="checkbox"/>	<input type="checkbox"/>
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## OTHER ART

*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
	C1	
	C2	
Examiner		Date Considered

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Examiner Unknown		August 26, 2003	2812

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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
	A33	5,000,178	03/19/1991	Griffith	128	419	03/18/1988
	A34	5,000,113	03/19/1991	Wang, et al.	118	723	12/19/1986
	A35	4,981,724	01/01/1991	Hochberg, et al.	427	255.37	10/28/1977
	A36	4,649,071	03/10/1987	Tajima, et al.	428	212	04/29/1985
	A37	2003/0111730	06/19/2003	Takeda, et al.	257	758	03/28/2001
	A39	2003/0089988	05/15/2003	Matsuura	257	758	08/13/2002
	A39	2003/0003765	01/02/2003	Gibson, Jr., et al.	438	760	01/02/2002
	A40	2003/0198742	10/23/2003	Vrtis	427	255.28	05/17/2002
	A41	2003/0194495	10/16/2003	Li, et al.	427	255.28	04/11/2002
	A42	2003/0211244	11/13/2003	Li, et al.	427	255.28	04/08/2003

**Foreign Patent Documents**

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B11						<input type="checkbox"/>	<input type="checkbox"/>
	B12						<input type="checkbox"/>	<input type="checkbox"/>

**OTHER ART**

*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.
	C4	Wu, et al., "Advanced Metal Barrier Free Cu Damascene Interconnects with PECVD Silicon Carbide Barriers for 90/65-nm BEOL Technology", 2002 IEEE, IEDM – Pages 595-598.
	C5	Tajima, et al. "Characterization of Plasma Polymers from Tetramethylsilane, Octamethylclotetrasiloxane, and Methyltrimethoxysilane' Journal of Polymer Science: Part A: Polymer Chemistry, 1987, Pages 1737-44.
	C6	

Examiner

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